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(54) DEVICE AND METHOD FOR ALIGNMENT OF OPTICAL AXIS

(57) An optical axis alignment apparatus 10 has a chuck 13 for holding an optical member 14, a chuck 16 for holding an optical member 15, a pushing mechanism, which pushes the chuck 1 to generate a predeter-

mined frictional force between the optical member 14 and the optical member 15, and actuators 18A to 18D. The actuators 18A to 18D have a piezoelectric element 51b which generates an impulsive inertial force by abrupt extension and contraction.

